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Sommario/riassunto	Fundamental Principles of Engineering Nanometrology provides a comprehensive overview of engineering metrology and how it relates to micro and nanotechnology (MNT) research and manufacturing. By combining established knowledge with the latest advances from the field, it presents a comprehensive single volume that can be used for professional reference and academic study. Provides a basic introduction to measurement and instruments Thoroughly presents numerous measurement techniques, from static length and displacement to surface topography, mass and force